

ELG Docket No. CYP01-016-CON2-US

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

First  
Named

Inventor:     Tinghao F. Wang

Serial No.:    10/071,809

Examiner:   Duy Vu Nguyen Deo

Filing

Date:           February 7, 2002

Group Art Unit No. 1765

Title:           METHOD FOR SELECTIVELY  
                  ETCHING SILICON AND/OR  
                  METAL SILICIDES

**AMENDMENT AND REQUEST FOR RECONSIDERATION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Applicants respectfully request reconsideration in light of the following  
amendments and remarks.